

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of:	)	
	)	
Noriaki Fukiage	)	Examiner: LaFond, Ronald D.
	)	
	)	
Serial No. 10/812,354	)	Art Unit: 1709
	)	
Filed: 03/30/2004	)	
	)	
For: Method of Improving the Wafer to Wafer Uniformity	)	
and Defectivity of a Deposited Dielectric Film	)	

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

AMENDMENT AND REQUEST FOR RECONSIDERATION

Dear Sir:

Responsive to the Office Action mailed 06/27/2007, the Applicant requests the Examiner to reconsider all pending claims in view of the following amendments and remarks.